Process Flow
as of 03/04/2002

Process Flow Key
- Photoresist
- P-type Si wafer
- Oxide
- PDMS
- Chromium
- Ion Implant (p)
- Ion Implant (p++)
- Ion Implant (n++)
- Au

1. Process Step: 1
   - Figure 1, AB
   - Figure 1, CD

2. Process Step: 4
   - Figure 2, AB
   - Figure 2, CD

3. Process Step: 8
   - Figure 3, AB
   - Figure 3, CD

4. Process Step: 11
   - Figure 4, AB
   - Figure 4, CD

5. Process Step: 14
   - Figure 5, AB
   - Figure 5, CD
Process Flow
as of 03/04/2002

Process Flow Key

- Photoresist
- P-type Si wafer
- Oxide
- PDMS
- Chromium
- Ion Implant (p)
- Ion Implant (p++)
- Ion Implant (n++)
- Au

Figure 6, AB. Process Step: 18
Figure 6, CD. Process Step: 18

Figure 7, AB. Process Step: 21
Figure 7, CD. Process Step: 21

Figure 8, AB. Process Step: ?
Figure 8, CD. Process Step: ?

Figure 9, AB. Process Step: ?
Figure 9, CD. Process Step: ?

Figure 10, AB. Process Step: ?
Figure 10, CD. Process Step: ?
Process Flow
as of 03/04/2002

Process Flow Key
- Photoresist
- P-type Si wafer
- Oxide
- PDMS
- Ion Implant (p)
- Ion Implant (p++)
- Ion Implant (n++)
- Au
- Chromium

Figure 11, AB. Process Step: ?
Figure 11, CD. Process Step: ?
Figure 12, AB. Process Step: ?
Figure 12, CD. Process Step: ?
Figure 13, AB. Process Step: ?
Figure 13, CD. Process Step: ?
Figure 14, AB. Process Step: ?
Figure 14, CD. Process Step: ?